



IPW

Docket No.: T2171.0214
(Patent)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

AOSHIMA, TOMOYASU

Application Number: 10/773,244

Confirmation No.: 7164

Application Date: February 9, 2004

Art Unit: n/a

For: ANISOTROPIC WET ETCHING OF SILICON

Examiner: Unassigned

STATUS INQUIRY

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir,

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office.

Respectfully Submitted,

Michael J. Scheer

Registration Number: 27,409

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Dated: September 14, 2005